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INFORMATI STATEMEN (Use as man)

## INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(Use as many sheets as necessary)

Comple	te if Known	
Application Number	10/817,133	
Filing Date	April 1, 2004	
First Named Inventor	WOODS et al.	
Art Unit	1746	
Examiner Name	Unassigned	
Attorney Docket Number	LAM2P475	

**U.S. Patent Documents** 

U.S. Fatent Documents						
Examiner	Cite No. <sup>1</sup>	Document Number	Publication	Name of Patentee or	Pages, Columns, Lines, where Relevant	
Initials		Number-Kind Code <sup>2 (# known)</sup>	Date MM-DD-YYYY	Applicant of Cited Document	Passages or Relevant Figures Appear	
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**Foreign Patent Documents** 

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**Non Patent Literature Documents** 

Examiner Initial	Cite No.	Include name of author (in CAPTIAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published
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Examiner: Initial if reference is considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.

¹Applicant's unique citation designation number (optional). ²See Kinds Codes of USPTO Patent Documents at <a href="https://www.uspto.gov">www.uspto.gov</a> or MPEP 901.04. ³Enter Office that Issued the document, by two-letter code (WIPO Standard ST.3). °For Japanese patent documents, the indication of the year of the reign of Emperor must precede the serial number of the patent document. <sup>6</sup>Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST.16 if possible. <sup>8</sup>Applicant is to place a check mark here if English language